

<b>Notice of References Cited</b>	Application/Control No. 10/614,102	Applicant(s)/Patent Under Reexamination CHEN, SHOEI-LAI	
	Examiner Mike Fatahiyar	Art Unit 2674	Page 1 of 1

**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-2002/0000974 A1	01-2002	Murai, Yasushi	345/163
	B	US-2003/0184521 A1	10-2003	Sugita, Go	345/163
	C	US-2002/0167470 A1	11-2002	Chung, Kuei-Lin	345/63
	D	US-2002/0118167 A1	08-2002	MEI et al.	345/163
	E	US-2002/0005834 A1	01-2002	Oh, Seung-Hwan	345/163
	F	US-6,498,458 B1	12-2002	Chen, Cliff	320/114
	G	US-6,392,635 B1	05-2002	Snyder, Robert F.	345/163
	H	US-6,225,981 B1	05-2001	Lu, Ho-Lung	345/164
	I	US-5,854,621	12-1998	Junod et al.	345/158
	J	US-6,909,421 B2	06-2005	Wang, Yung-Hui	345/163
	K	US-6,304,249 B1	10-2001	Derocher et al.	345/163
	L	US-			
	M	US-			

**FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
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	V	
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	X	

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